

Performance of the monolithic matrices of the H35DEMO chip before and after irradiation

S. Terzo, E. Cavallaro, R. Casanova, F. Förster,
S. Grinstein, C. Puigdengoles



*Test beam measurements in collaboration
with University of Geneva*



**UNIVERSITÉ
DE GENÈVE**

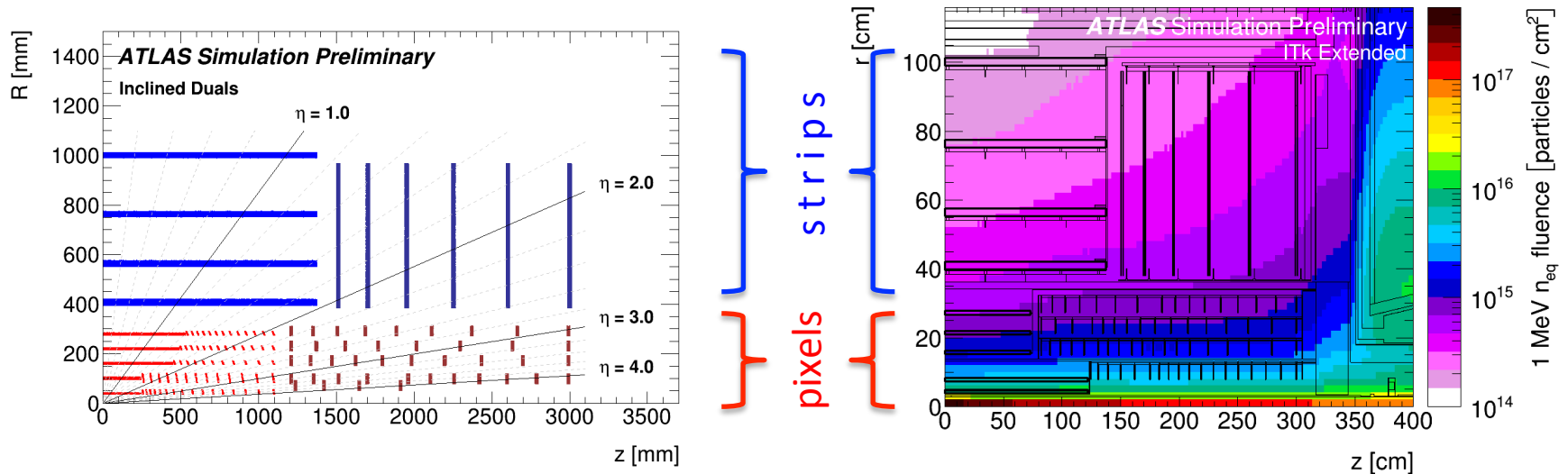
FACULTÉ DES SCIENCES

13th "Trento" Workshop
Munich, 20th February 2018

- The H35Demo large area demonstrator chip
- Monolithic matrix readout and tuning
- Test beam measurement and results
- Conclusions and outlook

The ITk upgrade for HL-LHC

Replace the whole ATLAS Inner Detector with a new full-silicon Inner Tracker (ITk)



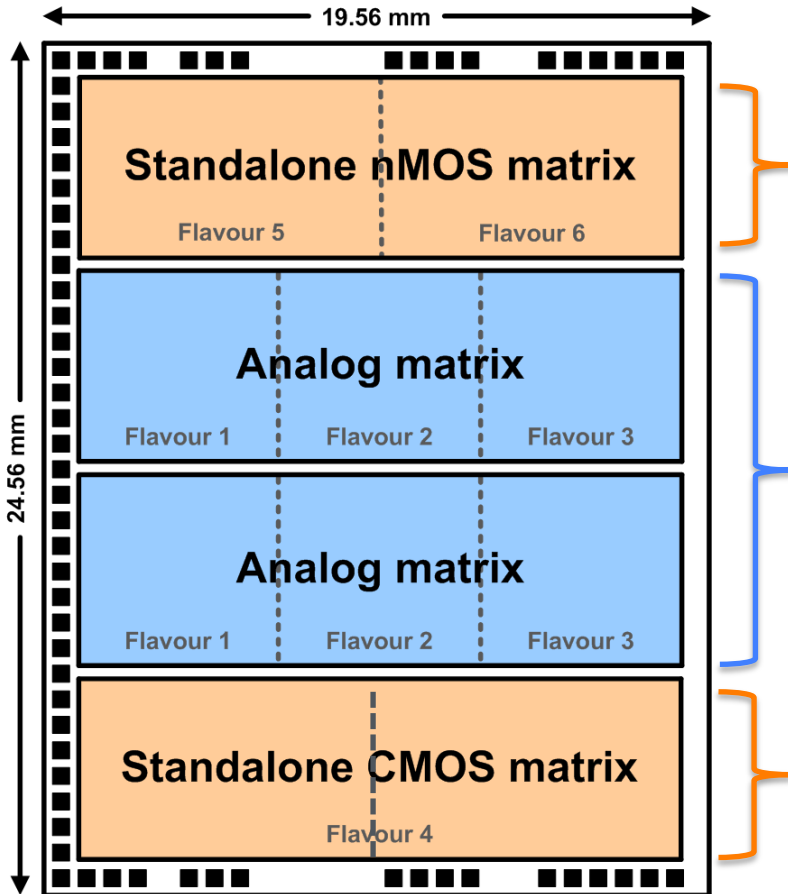
- New layout with 5 pixel barrel layers & large η coverage
- Sensor technologies under investigation:
 - Outer pixel layers (large area to cover)
 - HR/HV-CMOS pixel detectors $\rightarrow 1.5e15 n_{eq} cm^{-2}$
 - n-in-p planar silicon sensors (150 μm thick)
 - Inner pixel layers
 - Thin n-in-p planar silicon sensors (100 μm thick)
 - 3D silicon sensors (baseline for the innermost layer)



The H35 Demonstrator

AMS 350 nm High Voltage CMOS: different ρ : 20–80–200–1000 Ωcm

Designed by KIT, IFAE and Univ. of Liverpool



Standalone nMOS matrix:

- Digital pixels with in-pixel nMOS comparator
- Two flavors: with and without Time Walk (TW) compensation

Analog matrices (2 arrays):

- To be Capacitive Coupled (CC) to FE-I4 readout chips

Standalone CMOS matrix:

- Analog pixels with off-pixel CMOS comparator

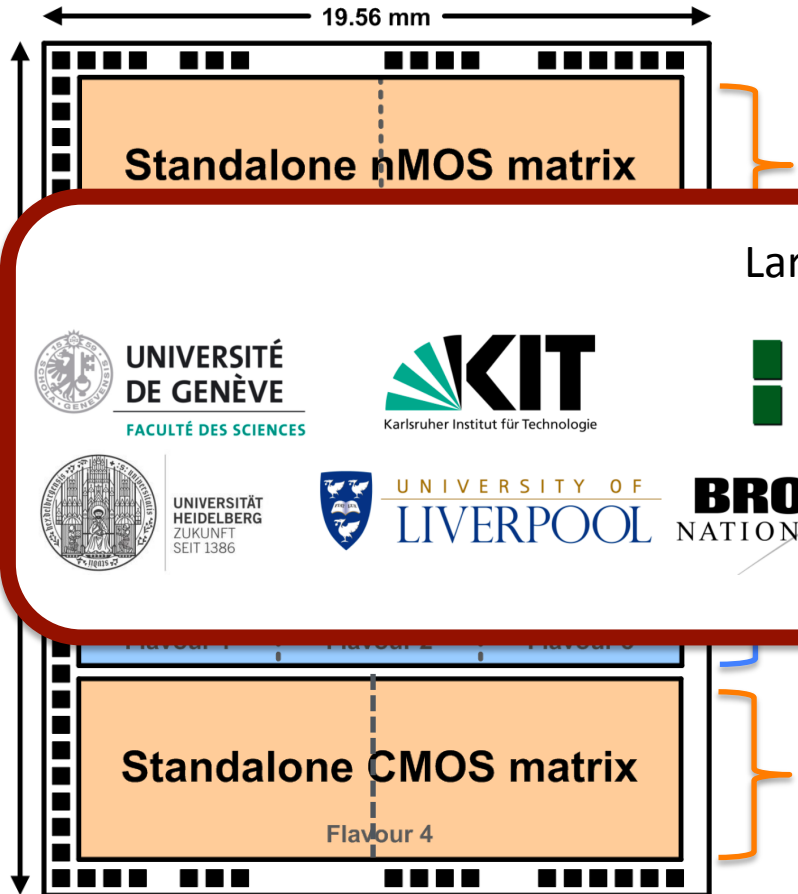


+ test structures without electronics for TCT studies
see D M S Sultan, M. Franks & A. Fehr talks

The H35 Demonstrator

AMS 350 nm High Voltage CMOS: different ρ : 20–80–200–1000 Ωcm

Designed by KIT, IFAE and Univ. of Liverpool



Standalone nMOS matrix:

Large collaboration

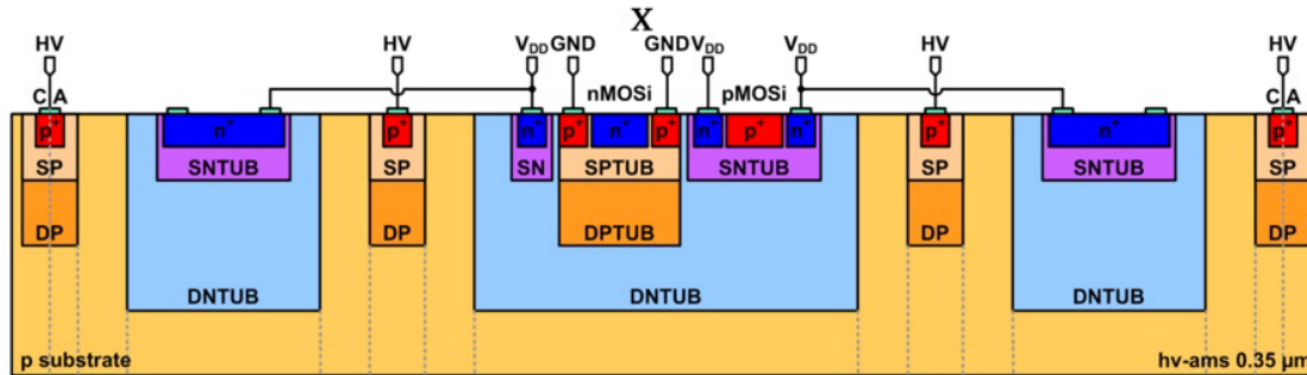
Standalone CMOS matrix:

- Analog pixels with off-pixel CMOS comparator



+ test structures without electronics for TCT studies
see D M S Sultan, M. Franks & A. Fehr talks

The H35 pixel structure



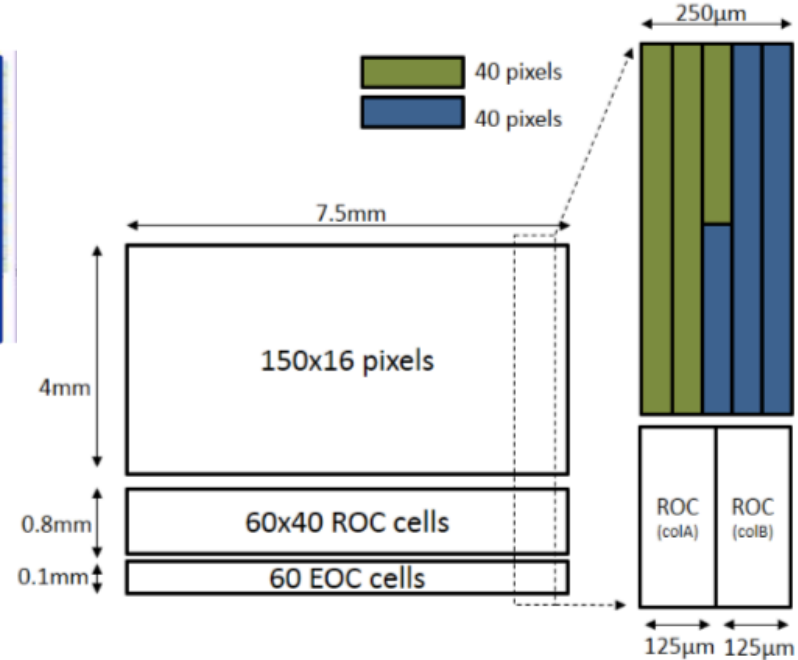
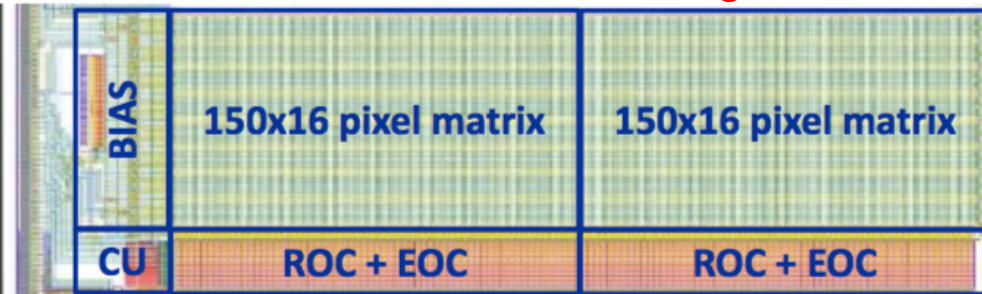
- Pixel size: $50 \times 250 \mu\text{m}^2$
- Large fill factor:
 - nMOS and pMOS transistors embedded in the same deep n-wells acting as collecting electrodes
 - p-substrate + 3 separate deep n-wells* to reduce the large capacitance
 - Full depletion & more uniform electric field
 - Short drift
- Bias voltage applied from the top
 - Single side processing
 - Bias voltage > 150 V

*all matrices but monolithic nMOS

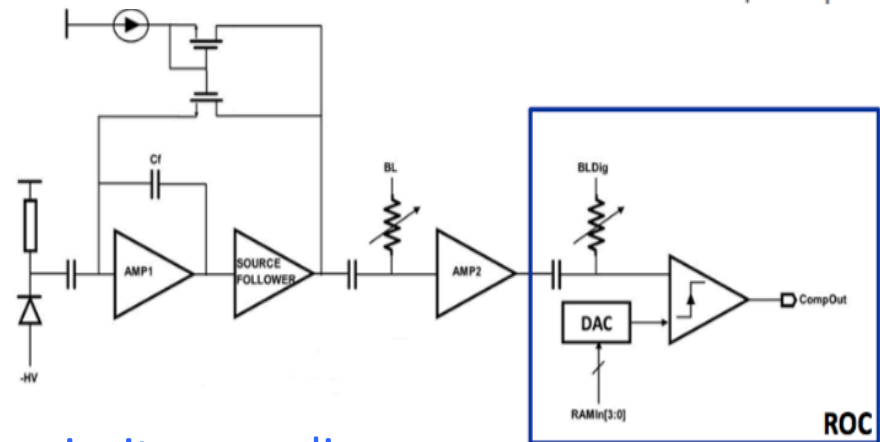
The monolithic CMOS matrix

Left matrix

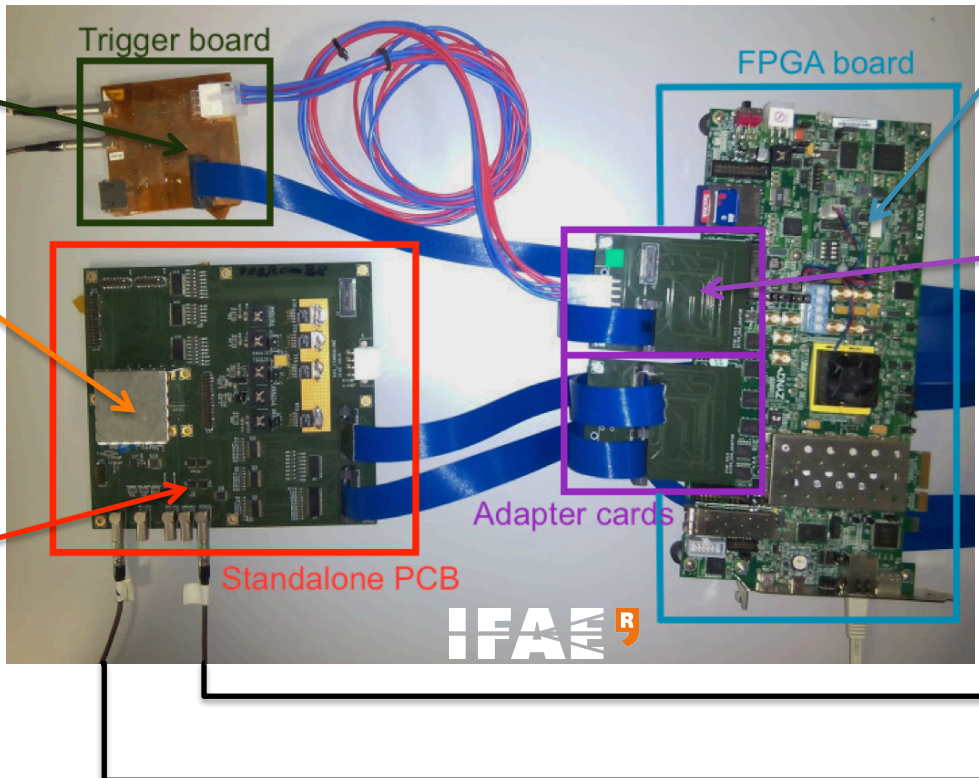
Right matrix



- Analog electronics on pixel
- Digital electronics in the periphery
 - ReadOutCell (ROC)
 - End Of Column (EOC)
 - Control Unit (CU)
- Off-pixel discriminators in the ROC:
 - 1 in the **Left** part
 - 2 the **Right** part (additional time-stamp for better timing)
- Column drain readout architecture with priority encoding
 - Trigger-less readout



Monolithic matrix readout at IFAE



Trigger board

- Trigger in
- Busy out
- RJ45

H35demo chip

- Both CMOS and nMOS matrices wire-bonded

H35demo PCB

- Voltage regulators
- Sensor bias input
- Injection pulse input
- Analog signal output

FPGA board


- Xilinx ZC706

Adapter PCBs

- 1x H35 PCB
- 1x test signals
- 1x trigger board

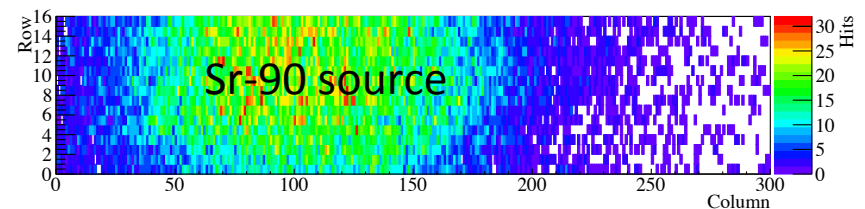
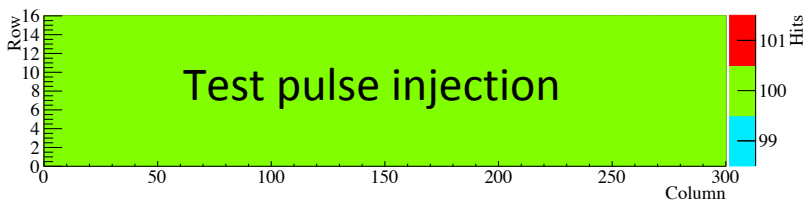
External

- Pulse generator
- Power supplies



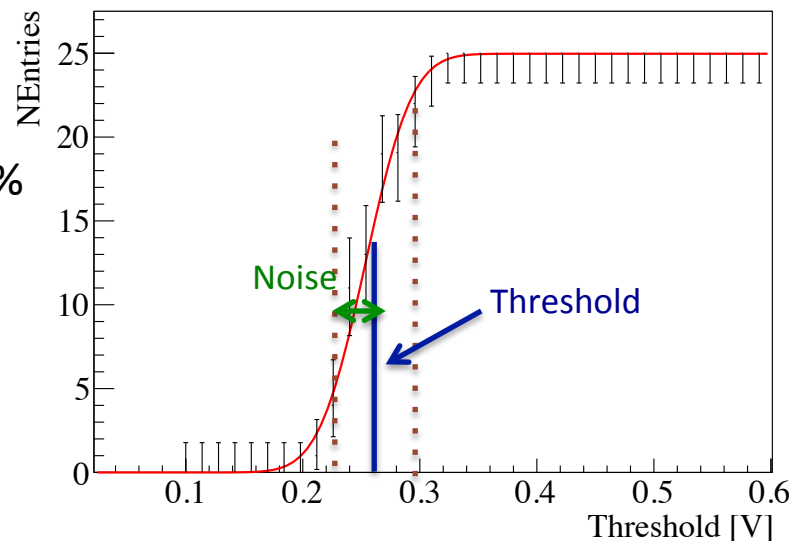
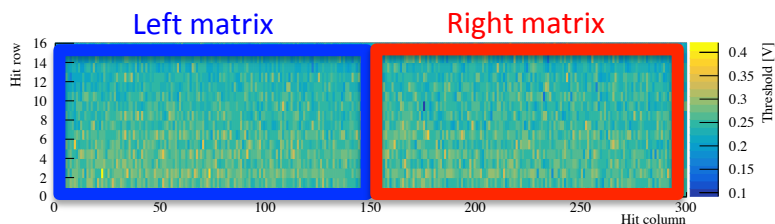
S. Terzo et al., JINST 12 (2017) no.6, C06009

PCBs, FPGA firmware and software developed at IFAE

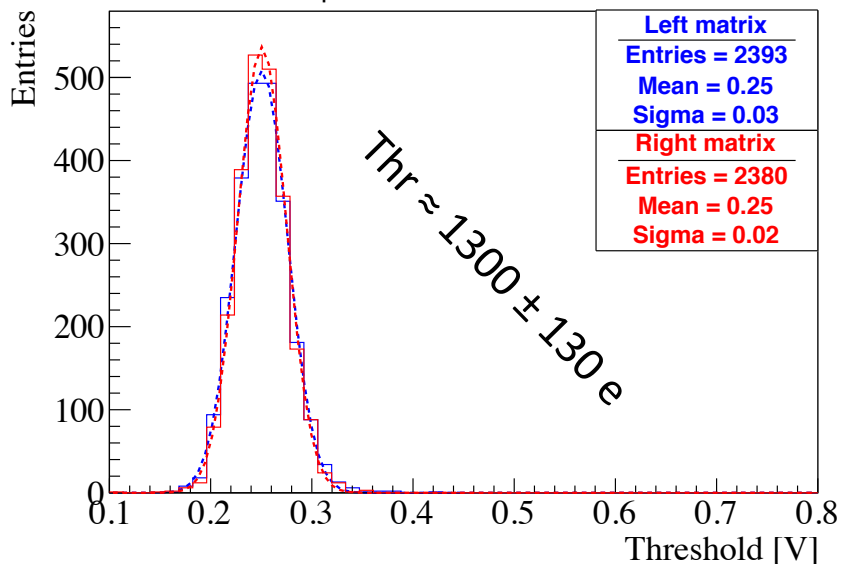


Monolithic matrix tuning

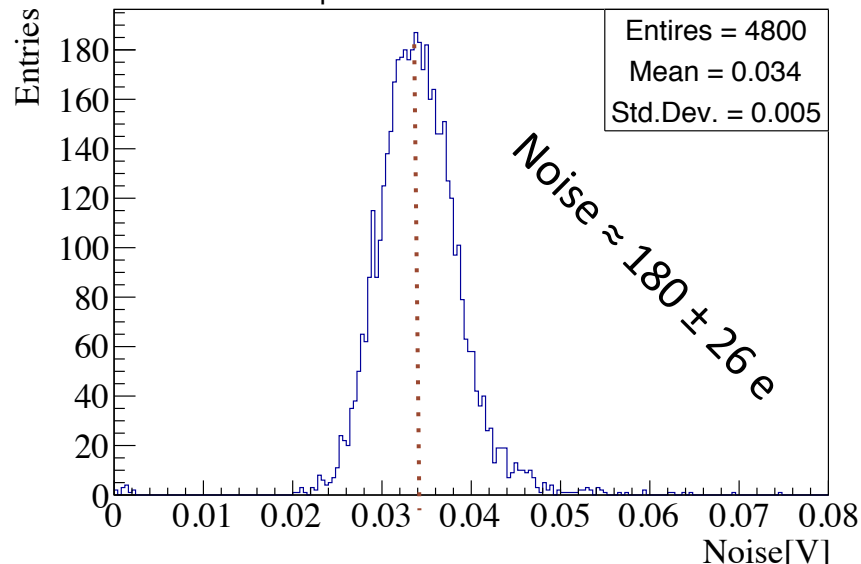
- CMOS matrix tuning (not irradiated):
 - Min. achieved threshold: 1300 ± 130 e
 - Threshold noise = 180 ± 26 e
 - Noise occupancy in 25 ns with less than 1% of pixel masked: $N_{occ} < 2 \times 10^{-7}$



D5: $\rho=200 \Omega\text{cm}$ - CMOS Matrix

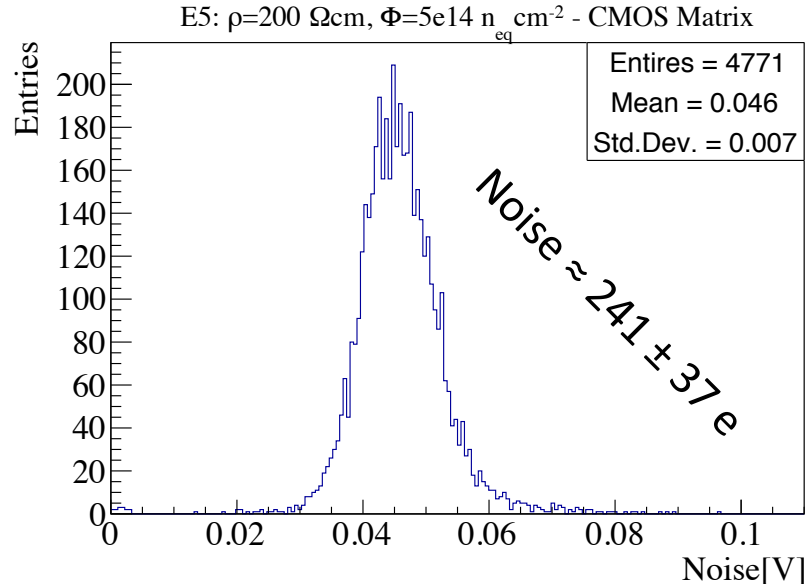
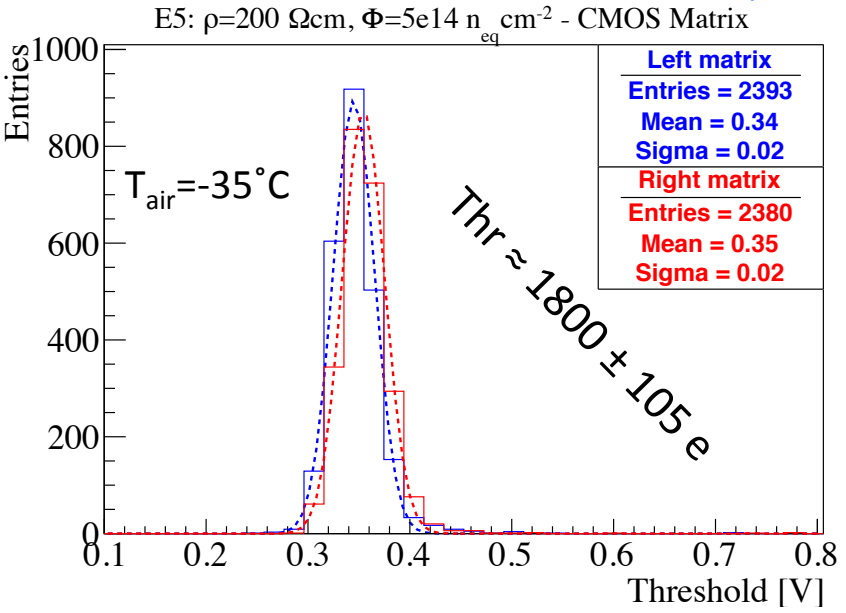


D5: $\rho=200 \Omega\text{cm}$ - CMOS Matrix

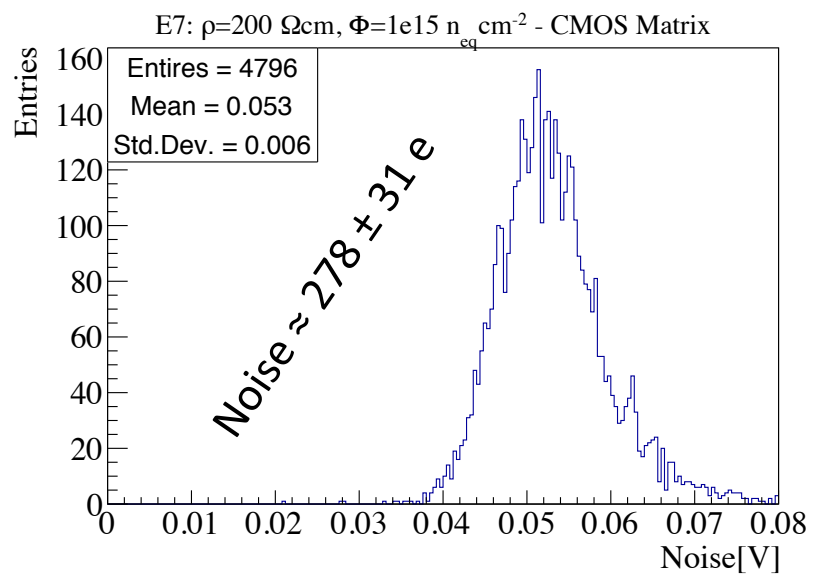
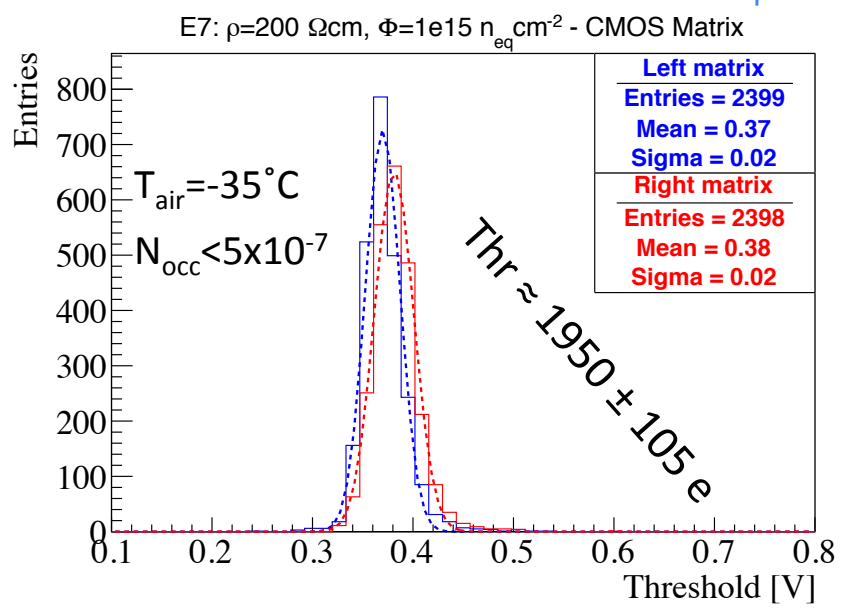


CMOS matrix tuning (irradiated)

Irradiated with neutrons to $5e14 \text{ n}_{eq} \text{ cm}^{-2}$



Irradiated with neutron to $1e15 \text{ n}_{eq} \text{ cm}^{-2}$



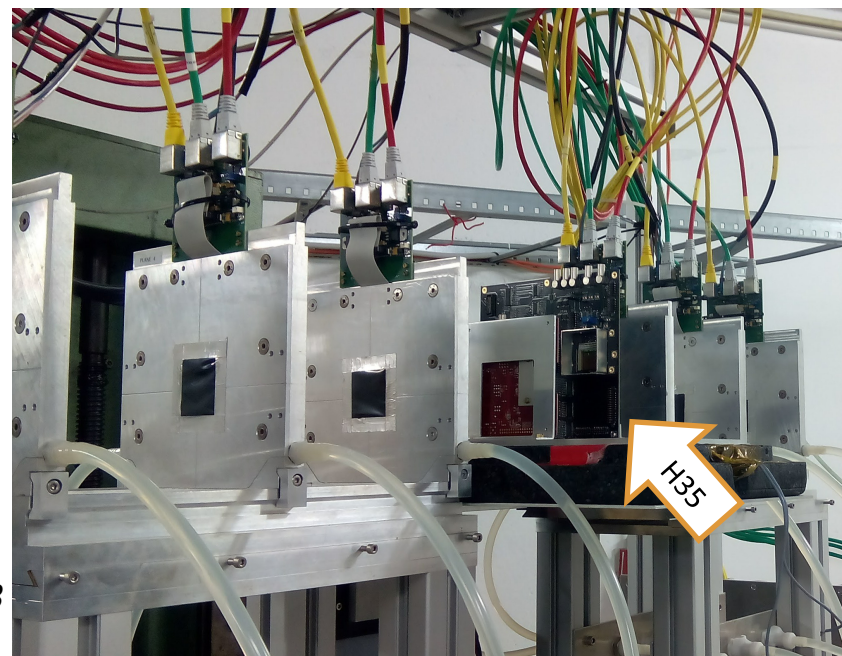
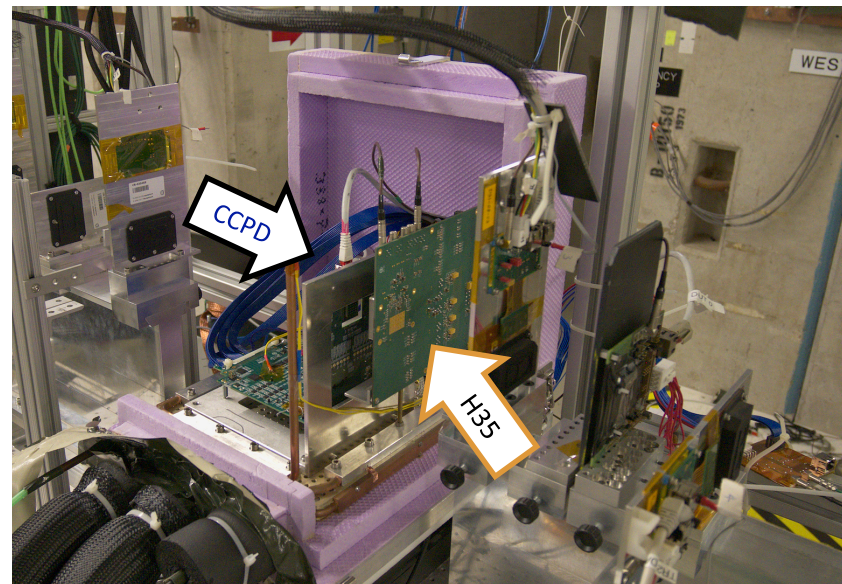
Beam test campaign in 2017

- Fermilab in April
 - 120 GeV protons
 - IFAE in collaboration with UniGe & Argonne Lab
 - UniGe FE-I4 telescope* + IFAE readout**
 - Not irradiated (20,80,200 Ω cm) + very first time irradiated 200 Ω cm
- CERN SpS in September
 - 180 GeV pions
 - IFAE in collaboration with UniGe
 - UniGe FE-I4 telescope* + IFAE readout**
 - 200 Ω cm neutron irradiated (@JSI) up to $1e15$
- DESY in November
 - 4 GeV electrons
 - With ATLAS ITk group
 - EUDET telescope + IFAE readout**
 - 200 Ω cm neutron (@JSI) and proton (@KIT) irradiated up to $2e15$

Analysis ongoing

*M. Benoit et al., JINST 11 (2016) no.7, P07003

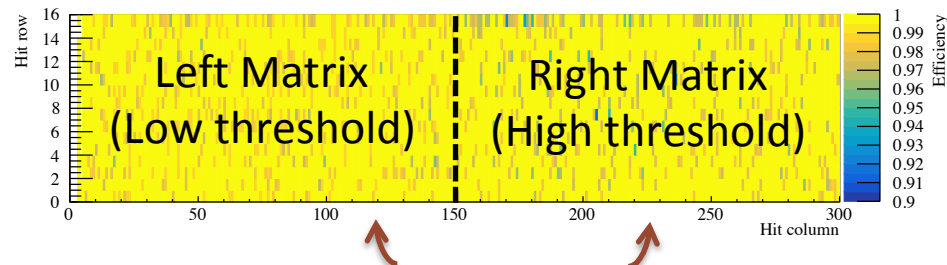
**S. Terzo et al., JINST 12 (2017) no.6, C06009



Hit efficiency results

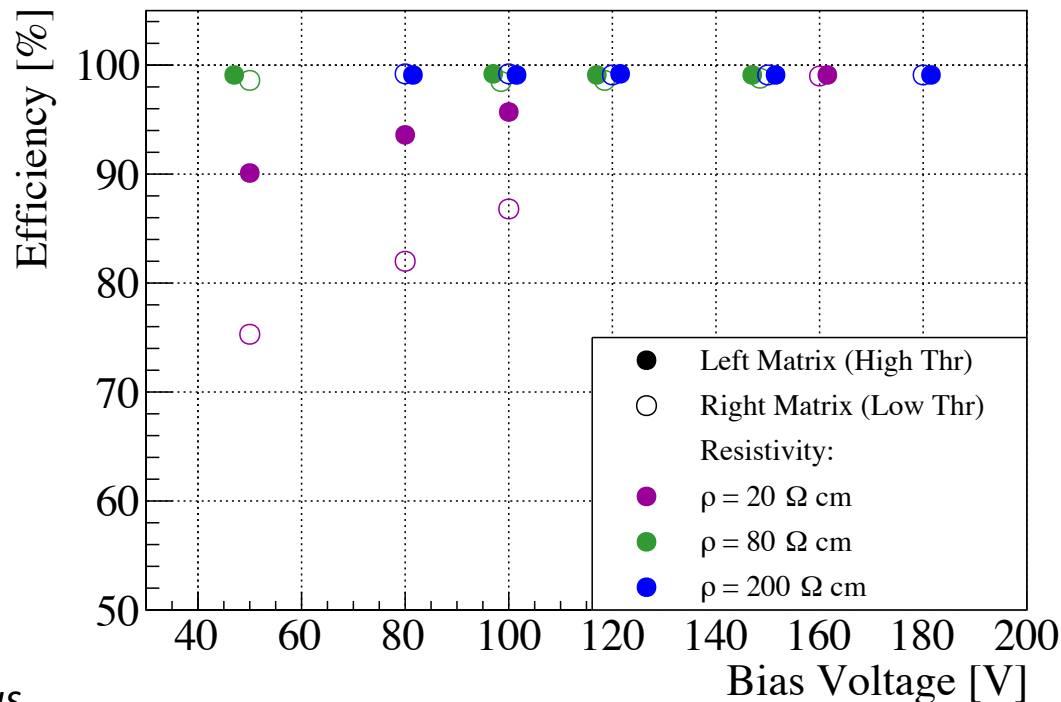
- H35demo CMOS matrix:
 - Different resistivities:
 - 20 – 80 – 200 Ωcm
 - Thresholds \approx 1300–1800 e
 - Analysis performed with the Proteus* framework

Efficiency map for 200 Ωcm @ 180 V



Efficiency calculated separately for the left and right part of the matrix due to the different off-pixel comparator settings

Before irradiation – CMOS matrix



Efficiency of >99% for sensors with resistivity \geq 80 Ωcm

20 Ωcm samples need about 160 V to reach full efficiency

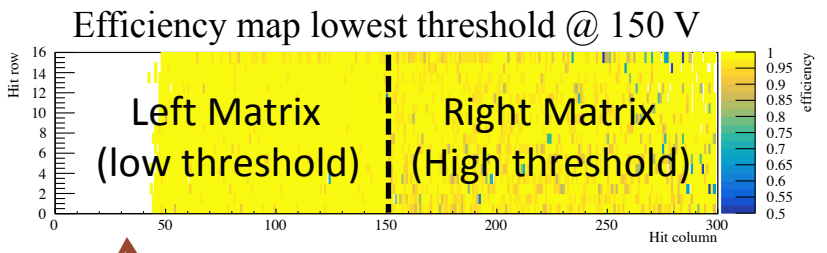
*<https://gitlab.cern.ch/unige-fei4tel/proteus>

Efficiency results from SpS beam test

200 Ω cm sample irradiated with neutrons at JSI

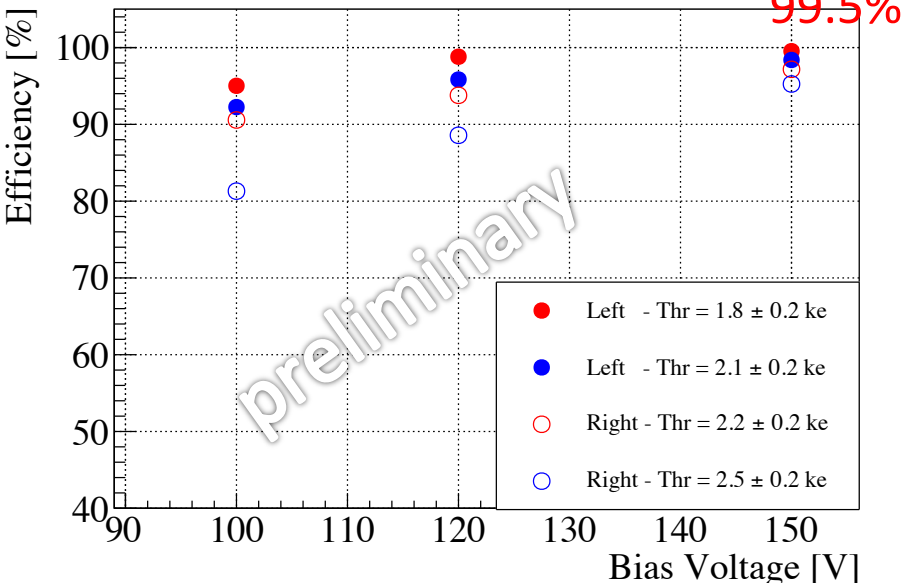
$5 \times 10^{14} \text{ n}_{\text{eq}} \text{ cm}^{-2}$

Depleted region of $\approx 50\text{-}60 \mu\text{m}$ at 120-150 V (from E-TCTs)



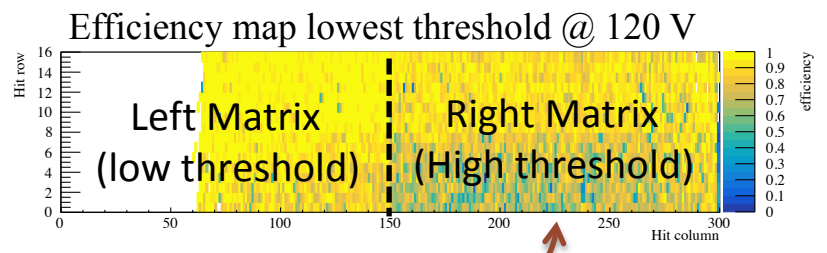
Cut due to the trigger window size

Sensor E5 - $\Phi = 5 \times 10^{14} \text{ n/cm}^2$



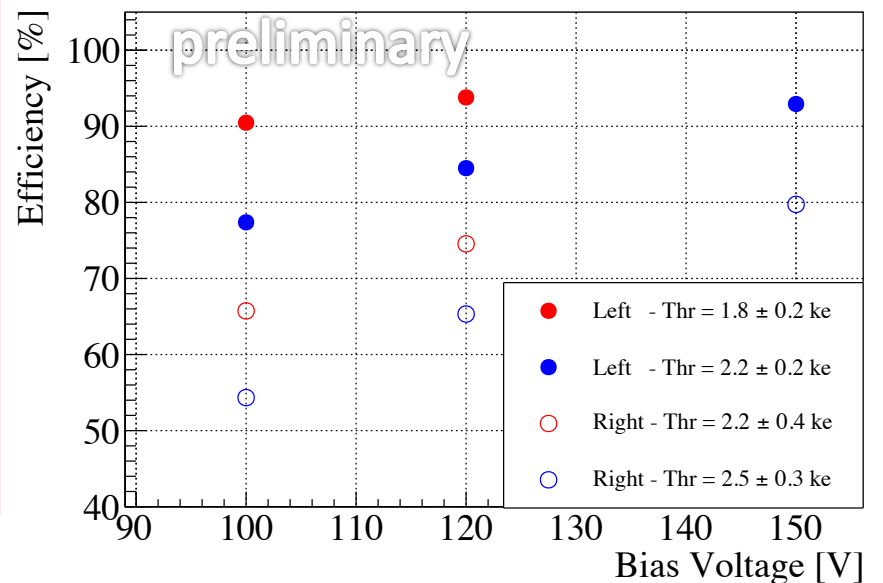
$1 \times 10^{15} \text{ n}_{\text{eq}} \text{ cm}^{-2}$

Depleted region of $\approx 60\text{-}70 \mu\text{m}$ at 120-150 V (from E-TCTs)



Up/down asymmetry not yet understood

Sensor E7 - $\Phi = 1 \times 10^{15} \text{ n/cm}^2$

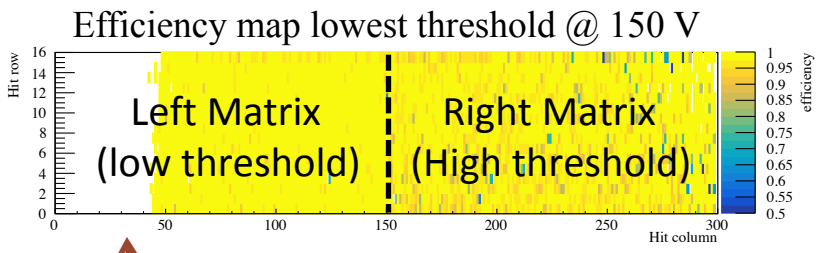


Efficiency results from SpS beam test

200 Ω cm sample irradiated with neutrons at JSI

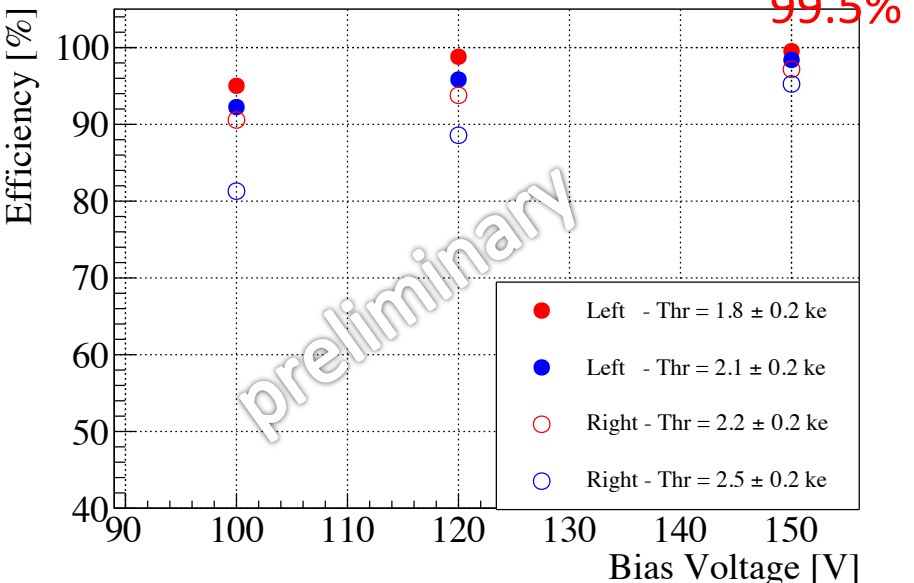
$5 \times 10^{14} \text{ n}_{\text{eq}} \text{ cm}^{-2}$

Depleted region of $\approx 50\text{-}60 \mu\text{m}$ at 120-150 V (from E-TCTs)



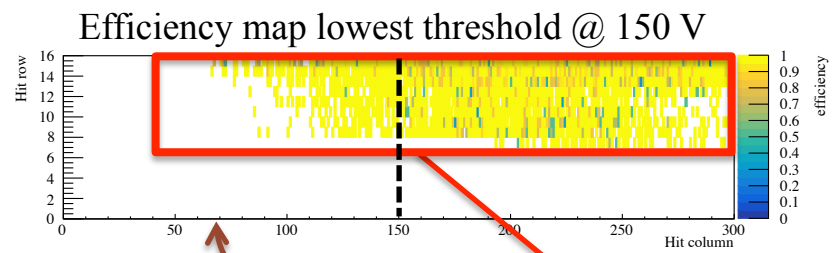
Cut due to the trigger window size

Sensor E5 - $\Phi = 5 \times 10^{14} \text{ n/cm}^2$



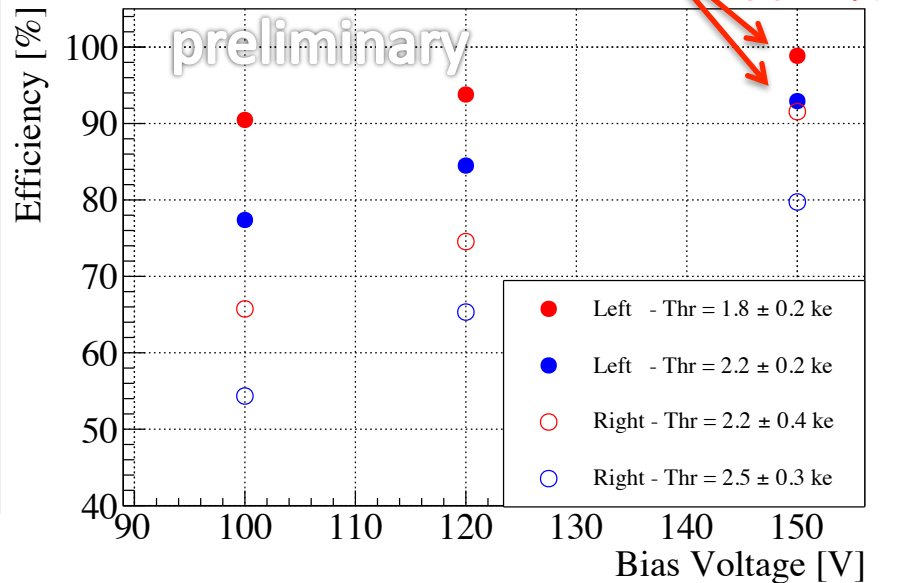
$1 \times 10^{15} \text{ n}_{\text{eq}} \text{ cm}^{-2}$

Depleted region of $\approx 60\text{-}70 \mu\text{m}$ at 120-150 V (from E-TCTs)



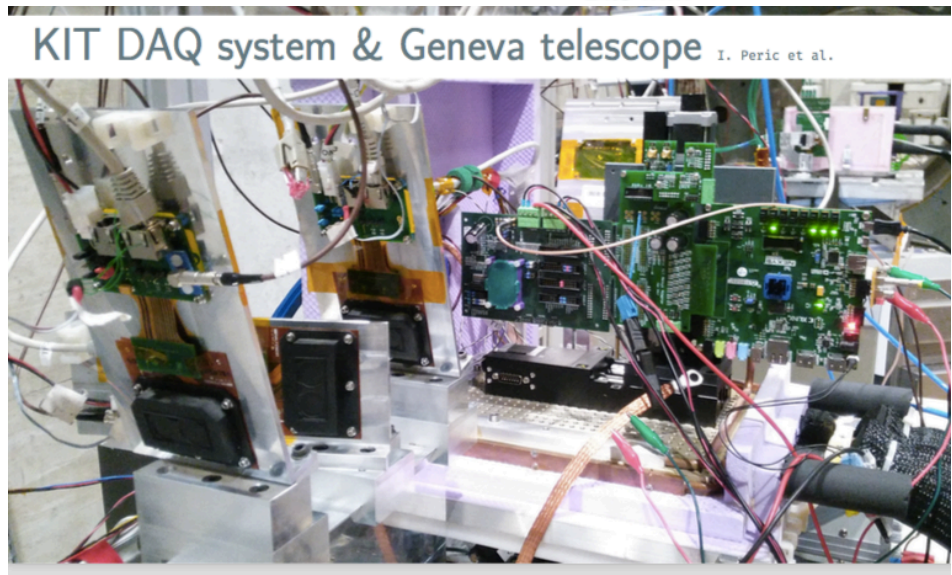
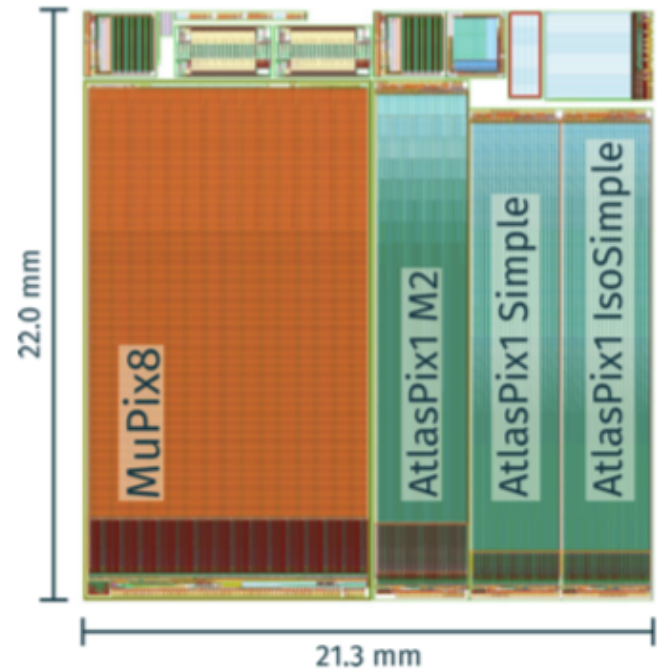
Beam accidentally displaced

Sensor E7 - $\Phi = 1 \times 10^{15} \text{ n/cm}^2$

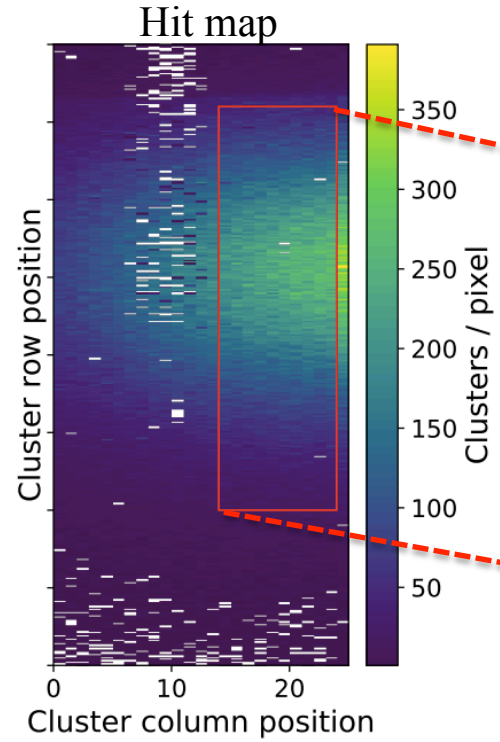


The ATLASPix prototype

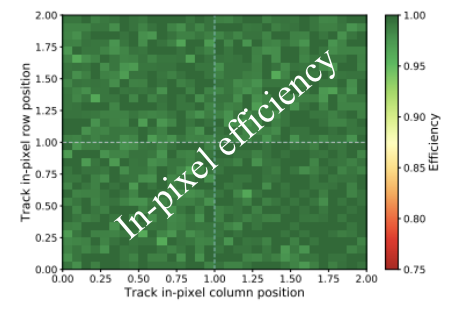
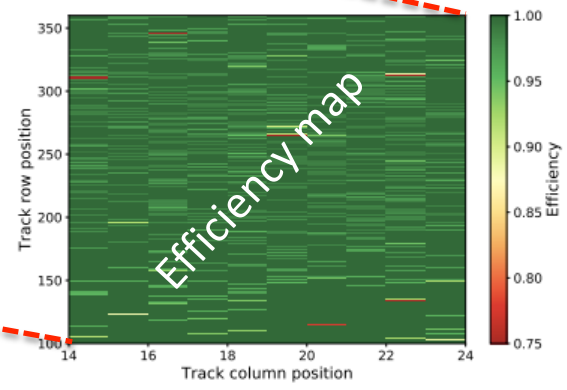
- Full scale monolithic prototype
 - AMS 180 nm CMOS process
 - Large fill factor
 - Designed at KIT, IFAE, Geneva, Heidelberg, Liverpool
- First Atlaspix1 chip:
 - M2 matrix:
 - Parallel-pixel-to-buffer architecture
 - 56x320 pixels
 - 60x50 μm^2 pitch
 - Simple & IsoSimple matrices
 - Column-drain architecture
 - 25x400 pixels
 - 130x40 μm^2 pitch
- First beam test of the Simple matrix
 - CERN SpS in November 2017
 - Collaboration of KIT and UniGe
 - UniGe FE-I4 telescope + KIT readout system
 - Chip operated at 10 MHz, 100 ns period



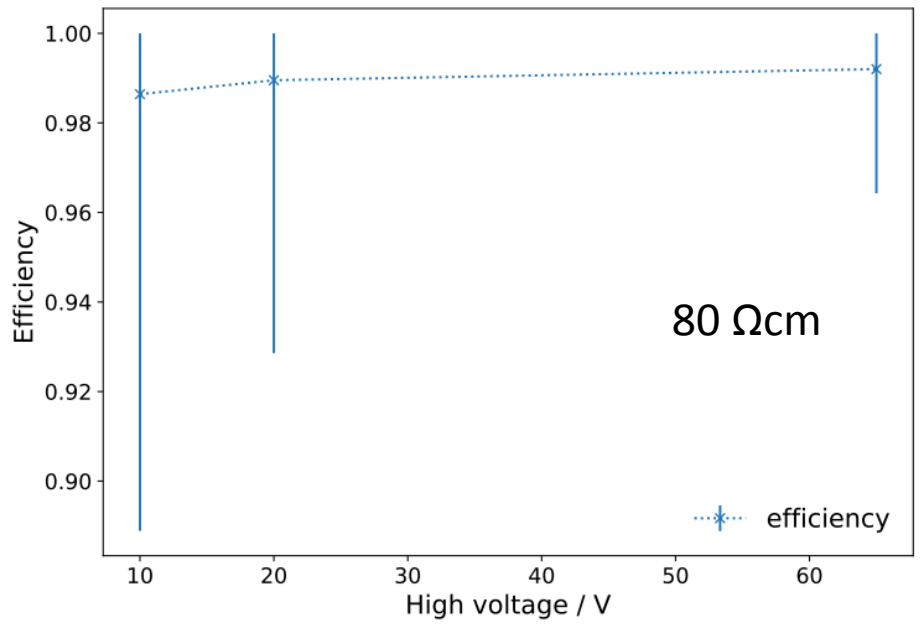
ATLASPix1: beam test results



- Region of Interest
 - Avoid tuning issues
 - Avoid low-statistic pixels



Efficiency of >99%
 Already high efficiency at low voltage



Conclusion & outlook

- Characterization of the H35Demo chip
 - New readout system developed at IFAE for the **monolithic** matrices
 - Tuning and readout at 320 MHz clock (25 ns events)
 - Full efficiency measured before irradiation for chips with resistivity $\geq 80 \Omega\text{cm}$ with a bias voltage $\geq 50 \text{ V}$

- Result of irradiated fully monolithic HV-CMOS pixel detectors for
 - Measured $200 \Omega\text{cm}$ samples after neutron irradiation to $1e15 n_{\text{eq}}\text{cm}^{-2}$
 - High efficiency with a bias voltage $>120 \text{ V}$ and threshold of 1800 e
 - Preliminary results show the possibility of reaching an efficiency of about 99% operating the detectors with a bias voltage of 150 V

- First promising results before irradiation of the new AtlasPix1 chip

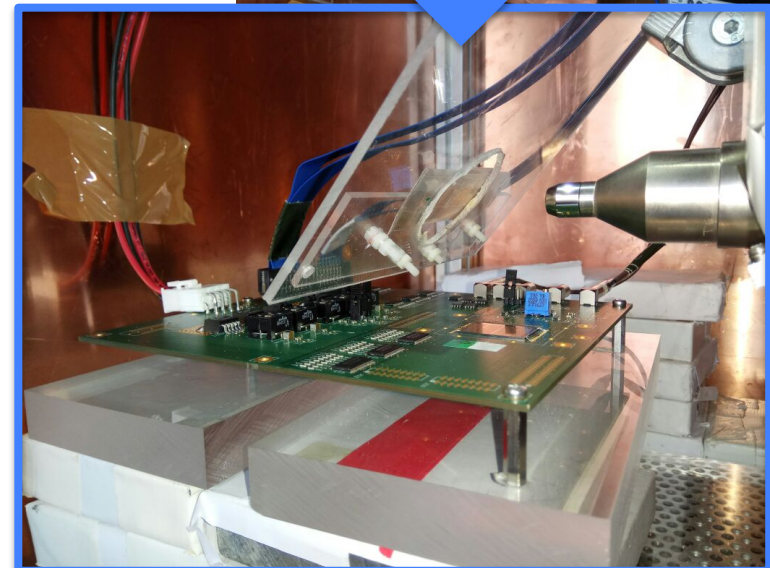
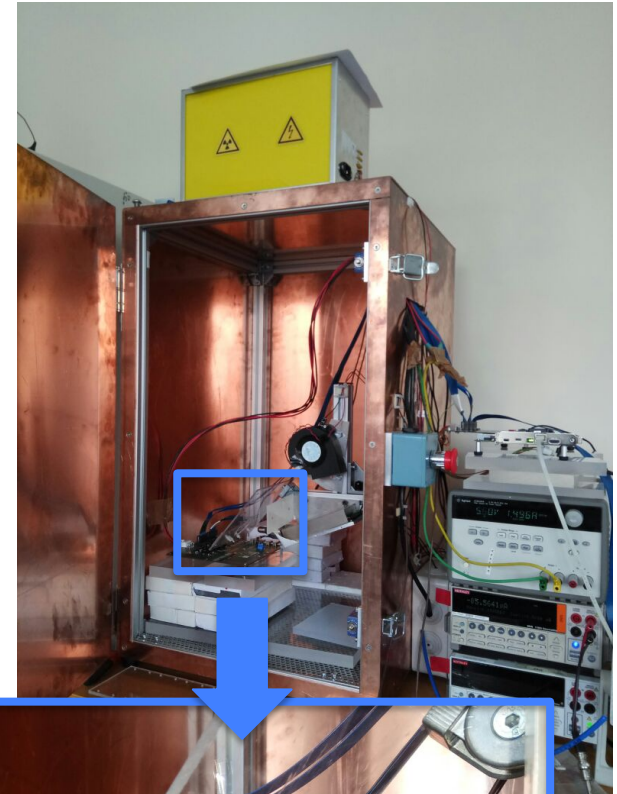
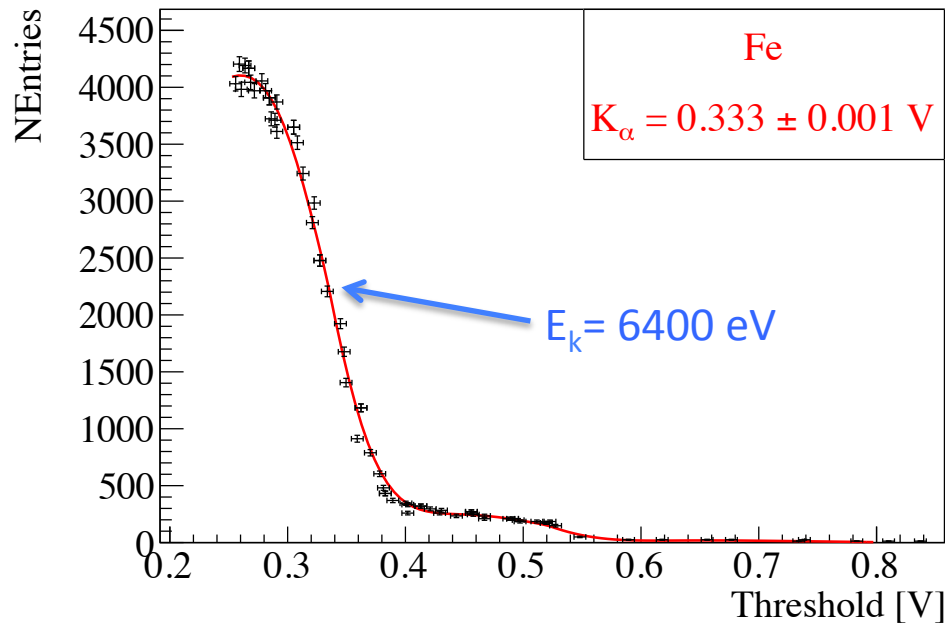
- What's next:
 - Analysis of H35Demo test beam @ DESY:
 - Neutron irradiated chips up to $2e15 n_{\text{eq}}\text{cm}^{-2}$
 - Proton irradiated chips up to $1e15 n_{\text{eq}}\text{cm}^{-2}$
 - Further characterization of the new ATLASPix designs in 180 nm before and after irradiation

Backup

H35 injection capacitance measurement

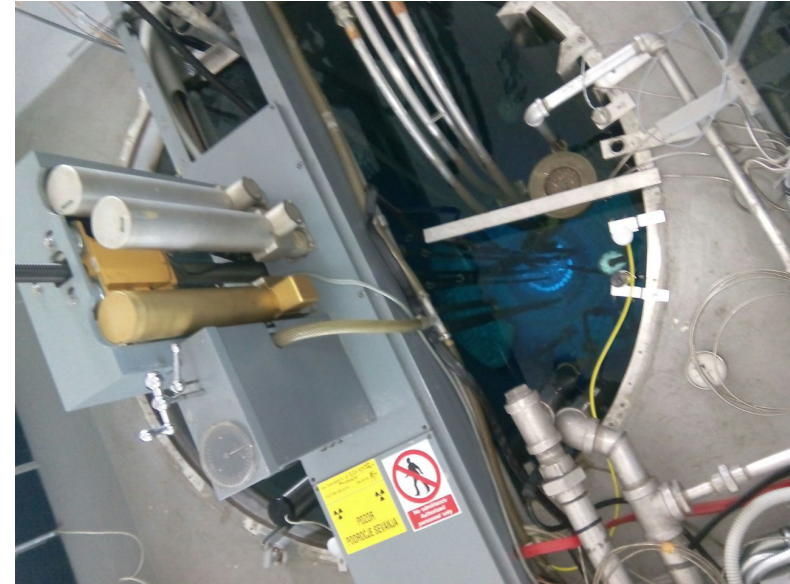
- First estimation of the injection capacitance for the CMOS matrix of the H35DEMO chip was obtained from simulations: 0.84 fF
- Measured also with the X-ray fluorescence setup at CERN
 - Very first estimations in agreement with the simulated value

S Curve Pixel 187 14

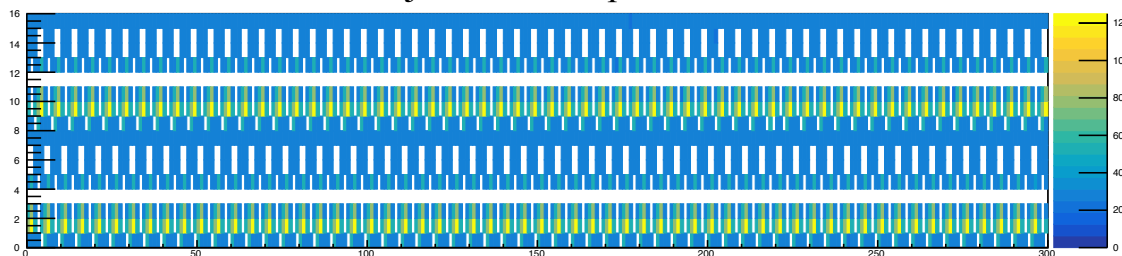


Further irradiations

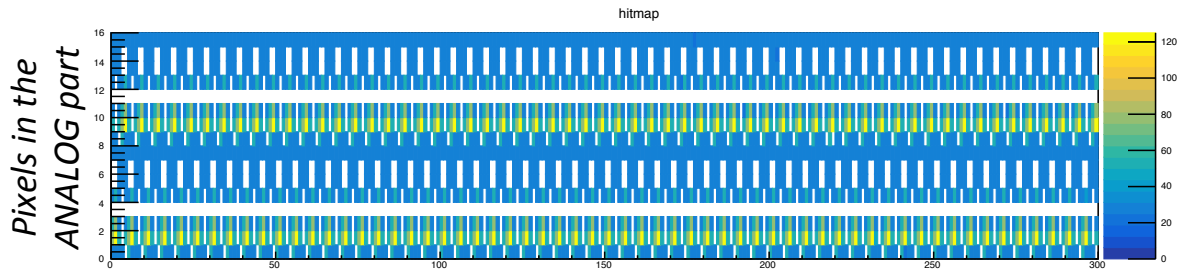
- 200 Ωcm chips have been irradiated with neutrons in the TRIGA reactor in Ljubljana up to $2 \times 10^{15} \text{ n}_{\text{eq}} \text{ cm}^{-2}$
- And at KIT with 23 MeV protons up to $1 \times 10^{15} \text{ n}_{\text{eq}} \text{ cm}^{-2}$
- We observed a digital pattern in the injection test:
 - After proton irradiation $\geq 1 \times 10^{14} \text{ n}_{\text{eq}} \text{ cm}^{-2}$
 - After neutron irradiation $\geq 1 \times 10^{15} \text{ n}_{\text{eq}} \text{ cm}^{-2}$ at low temperature
- The number of pixel misbehaving increases with the fluence and it is particularly enhanced for proton irradiations



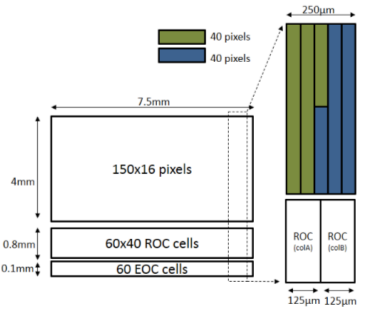
Injection test – protons 1×10^{15}



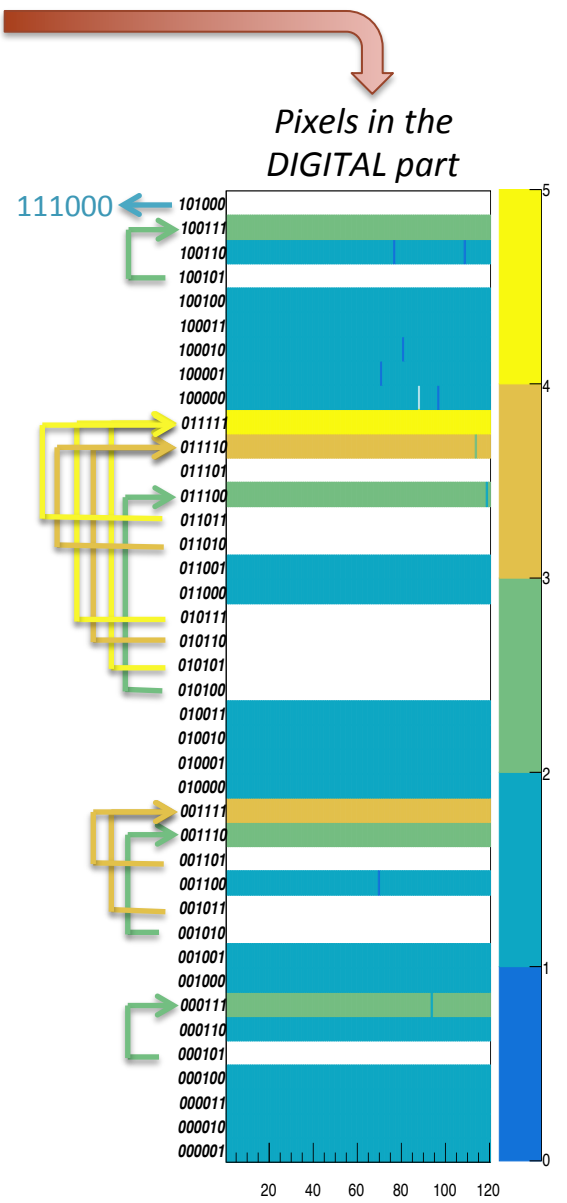
Address crosstalk



- The 16x300 analog pixels in the CMOS matrix are connected one-to-one to 40x120 pixels in the digital periphery
- The addresses are generated in the periphery with adjacent transistors
- Due to strong capacitive couplings between adjacent lines it is possible to have crosstalk between addresses
- This has been corrected in the design of the H18 ATLASPix1 by adding additional capacitors between the lines

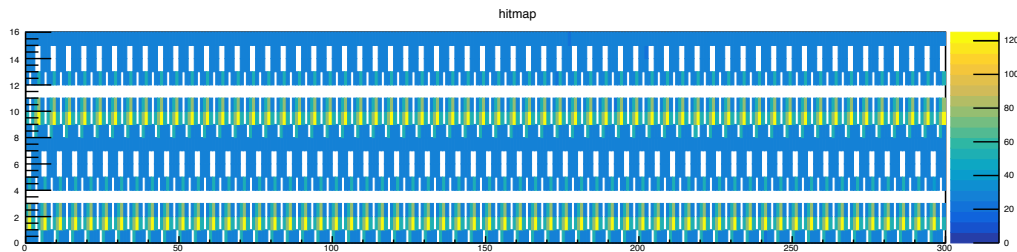


1 0 1
 1-> 0 <-1
 1 1 1

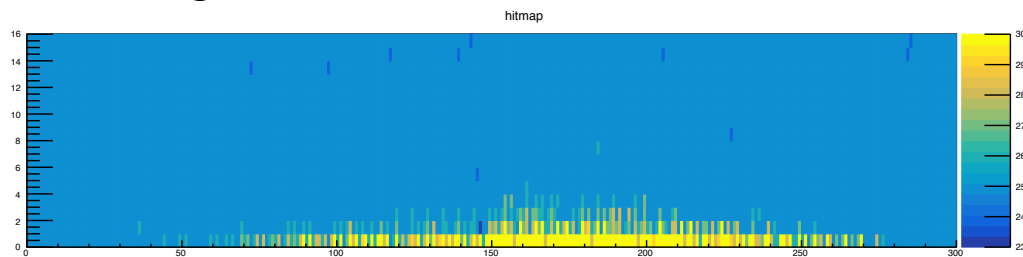


Solution

- Standard settings of the digital voltage: $V_{DD} = 3.3V$



- Increasing V_{DD} from 3.3V \rightarrow 5V

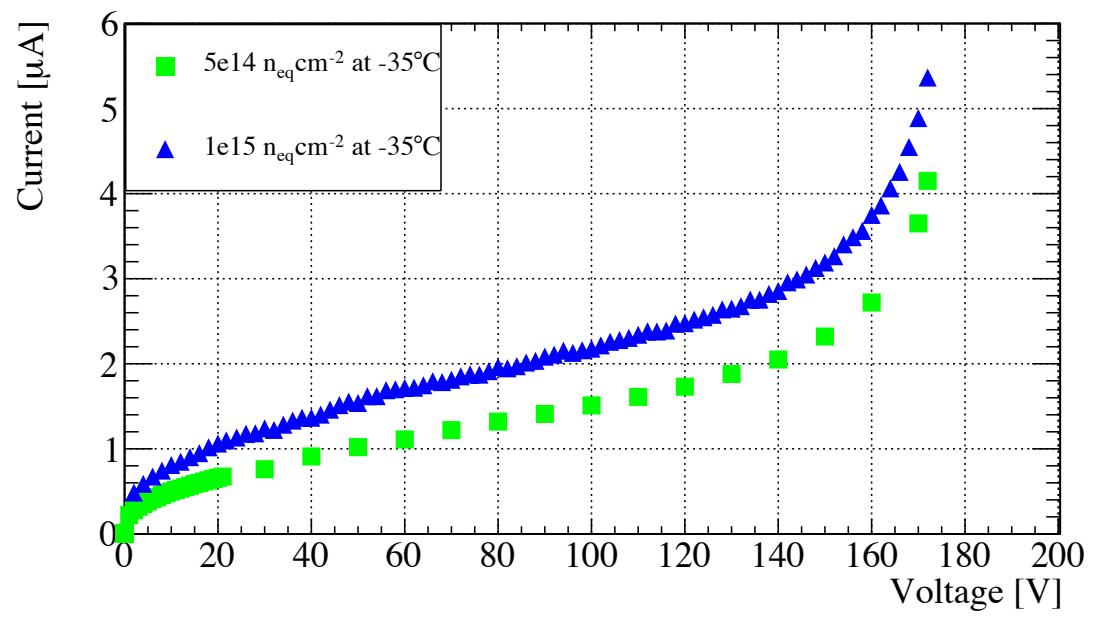
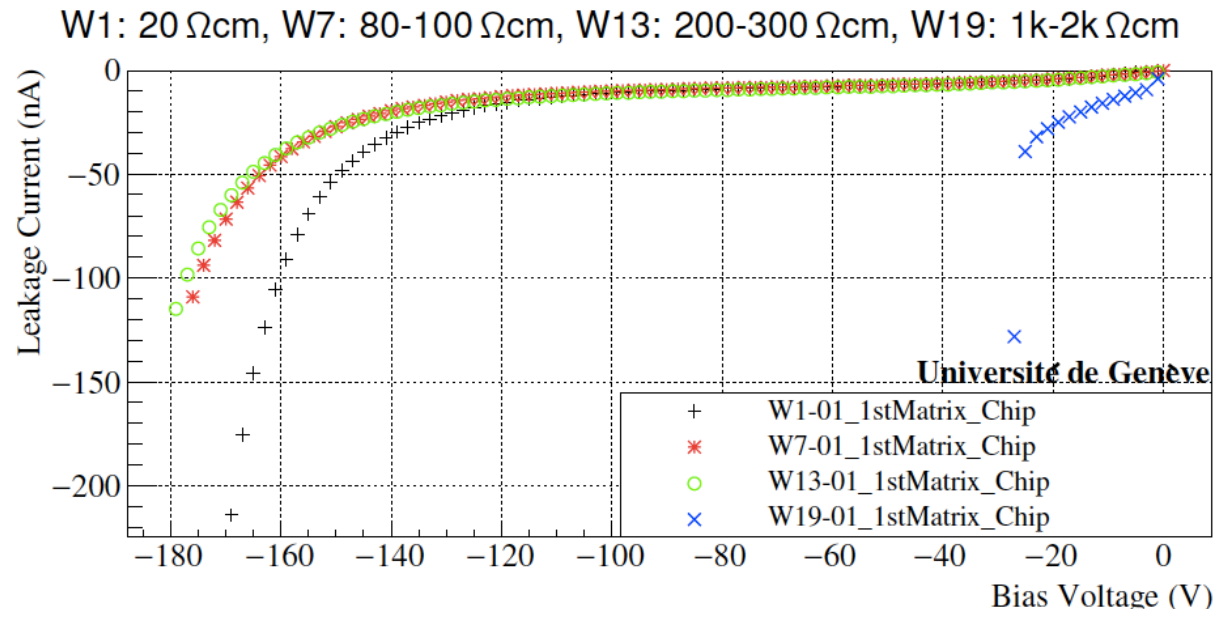


+1.7V

Noisy pixels in the first rows

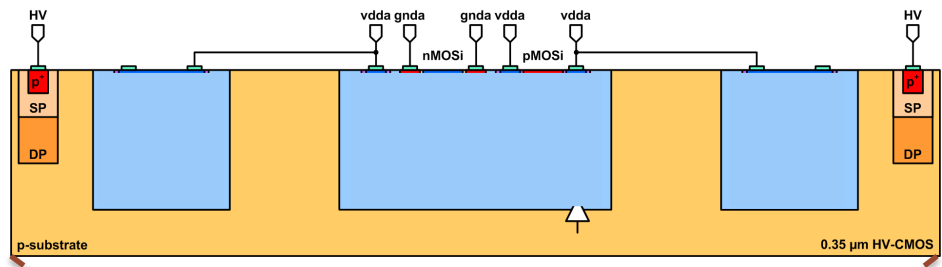
- The digital voltage needs to be increased depending on the irradiation levels:
 - Proton irradiated samples require very high V_{DD} which lead to a noise increase
 - Neutron irradiated samples require instead moderate V_{DD} increase (less than 4V)

H35 – matrix IVs



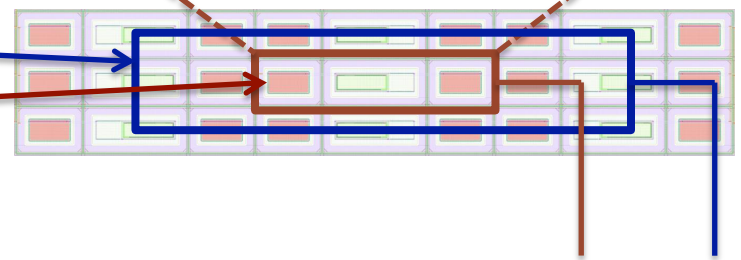
Sensor characterization

- **H35 pixel cell structure**
 - p-substrate + 3 deep n wells
 - Lower capacitance (noise, timing)
 - Reduce trapping
 - Bias from the top -> single sided



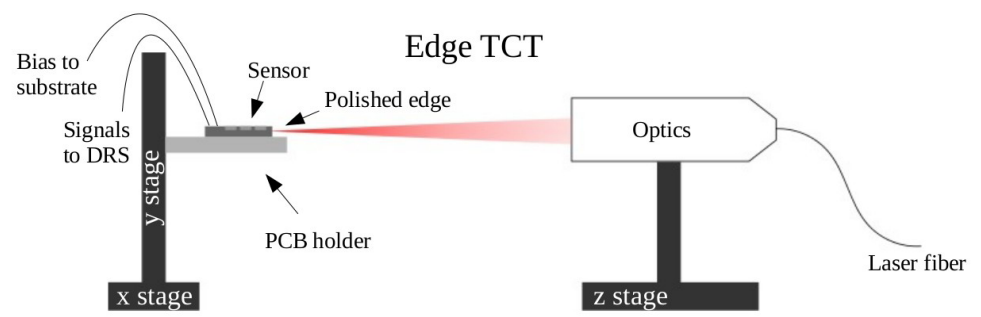
- **Characterization of H35 test structures:**

- 3x3 pixel structures w/o electronics
- External pixels shorted together
- Separate readout of the central pixel
- $\rho = 80 \Omega\text{cm} - 200 \Omega\text{cm} - 1 \text{k}\Omega\text{cm}$



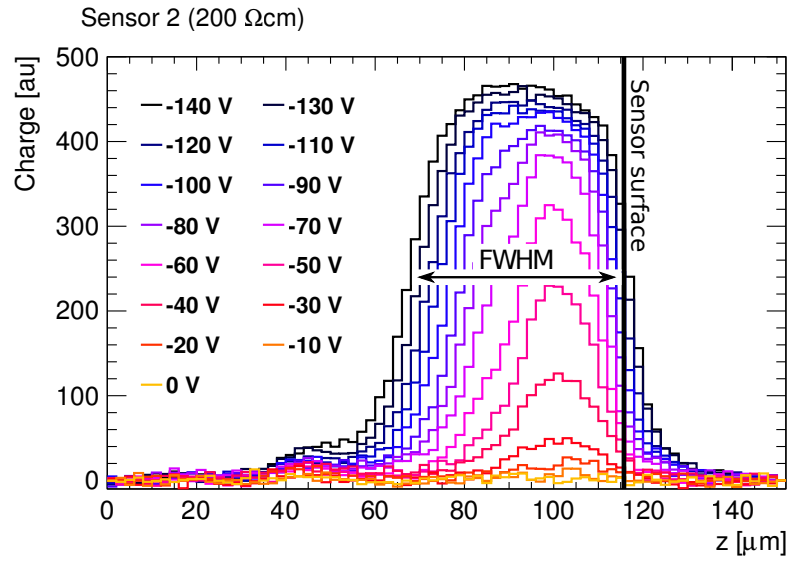
- **The Edge-TCT setup:**

- Infra-red laser (1064 nm)
 - Beam spot about 10 μm FWHM
 - Pulses of about 500 ps
- Readout: DRS4 evaluation board
 - 700 MHz bandwidth
 - 5 GSPS
 - 200 ns sampling depth
 - Four channels: 1 \times trigger, 1 \times beam monitor, 2 \times readout



Depletion: before irradiation

- Depletion depth is defined by the FWHM of the charge collection profile

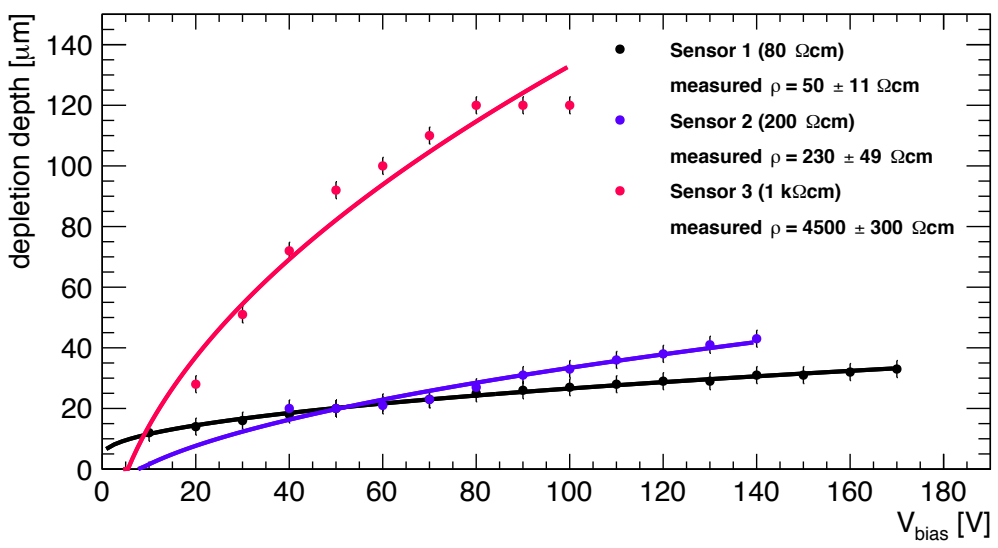


- Resistivity obtained fitting the depletion depth as a function of the bias voltages

$$d(V) = d_0 + \alpha \sqrt{\rho V}$$

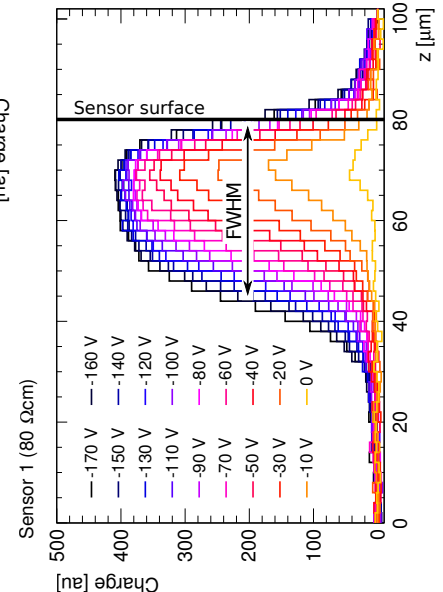
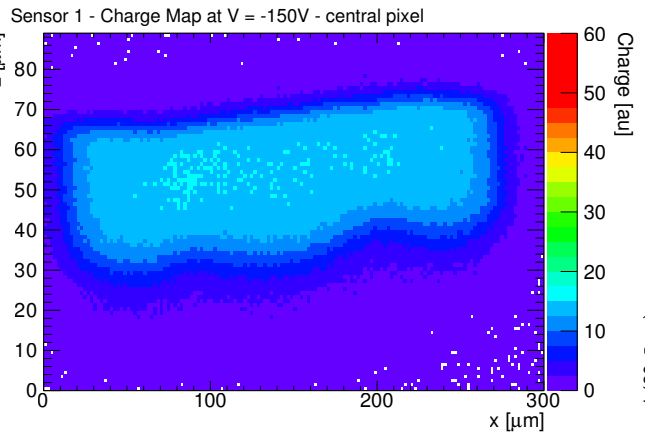
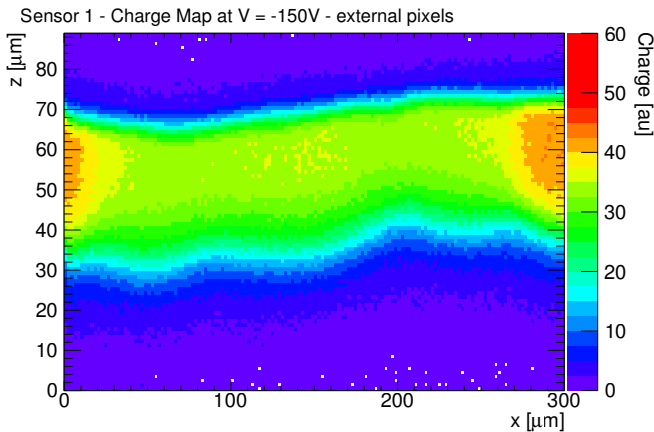
with $\alpha = \sqrt{2\epsilon\epsilon_0\mu}$

	ρ nominal	ρ measured
Sensor 1	80 Ω cm	50 \pm 11 Ω cm
Sensor 2	200 Ω cm	230 \pm 49 Ω cm
Sensor 3	1000 Ω cm	4500 \pm 300 Ω cm



Depletion: before irradiation

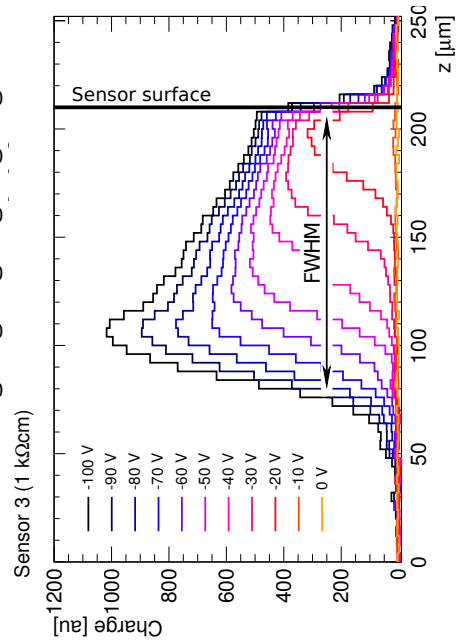
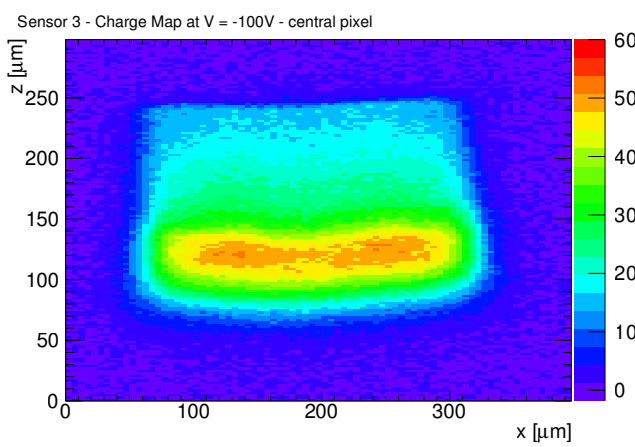
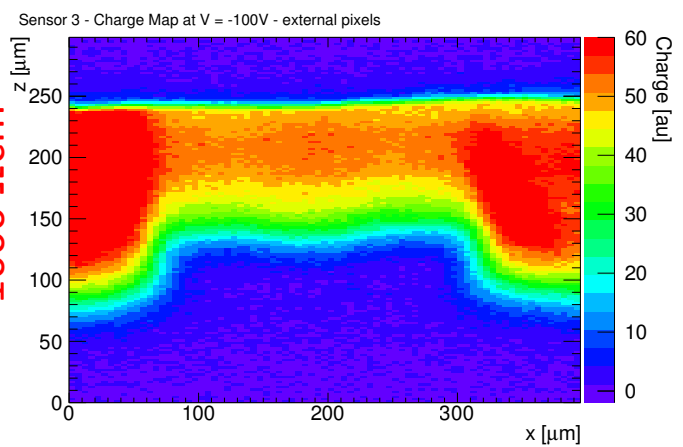
80 Ω cm



External pixels

Central pixel

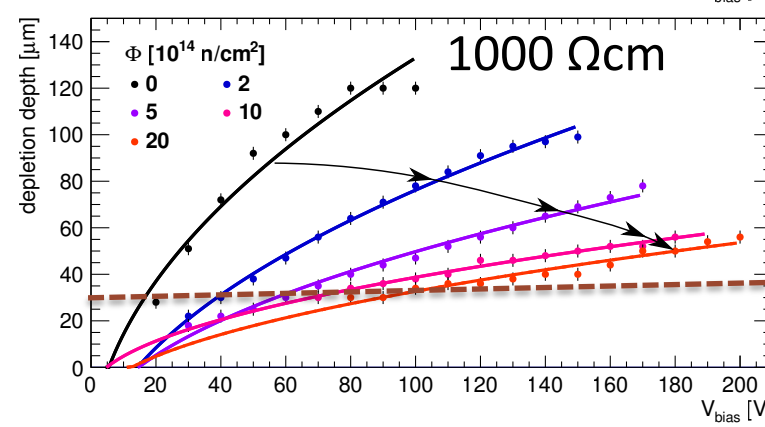
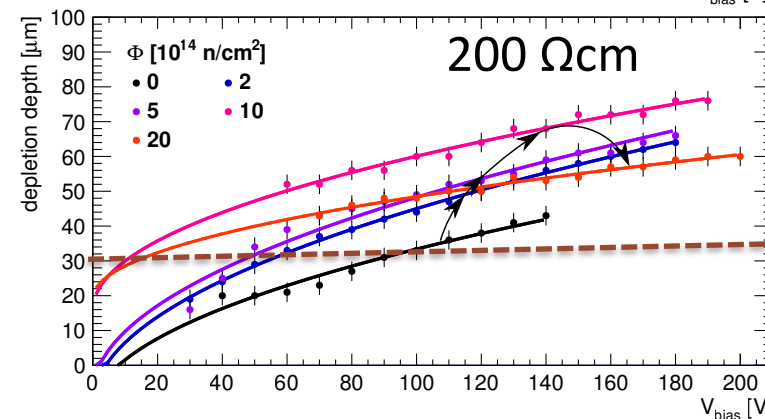
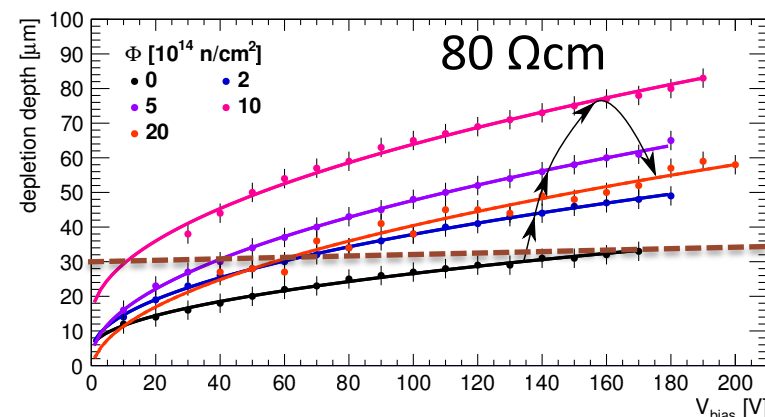
1000 Ω cm



When depletion gets larger of 100 μ m the central pixel starts to collect charge from the neighboring pixels

Depletion: after irradiation

- Irradiation at the TRIGA neutron reactor at JSI, Ljubljana:
 - Now: **2e14**, **5e14**, **10e14**, **20e14** $n_{eq}cm^{-2}$
 - Next steps: 5e15 and 1e16 $n_{eq}cm^{-2}$
- Acceptor removal effect visible for lower substrate resistivities which leads to an increase of the depletion depth after irradiation up to $2e15 n_{eq}cm^{-2}$
- Due to the low initial acceptor concentration in the 1000 Ωcm sample the creation of stable acceptors dominates and the depletion depth decreases after irradiation



Effective doping concentration

- Effective doping concentration obtained from:

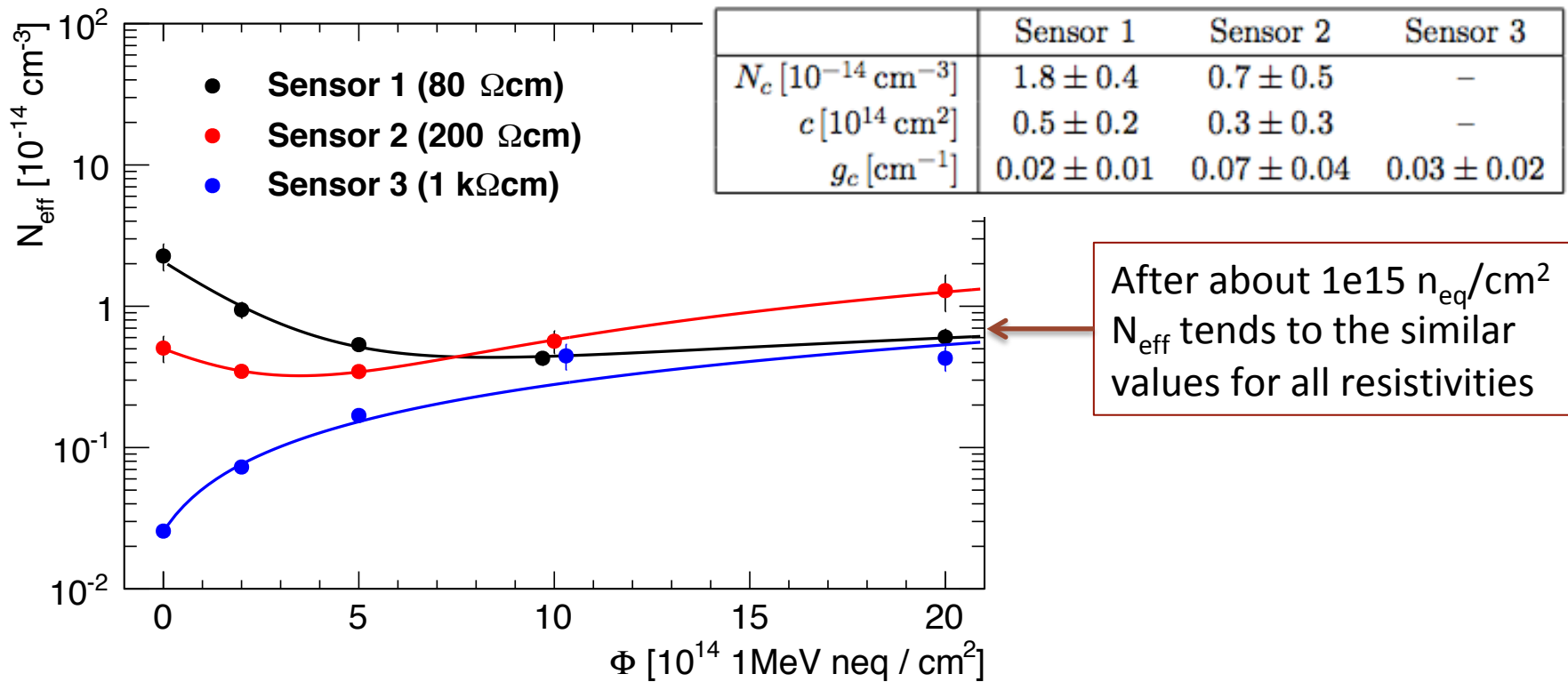
$$d(V) = d_0 + \alpha\sqrt{\rho V} = d_0 + \sqrt{\frac{2\epsilon\epsilon_0}{eN_{eff}}} V$$

$$N_{eff} = \underbrace{N_{eff0}}_{\text{Initial doping}} - \underbrace{N_c \cdot (1 - \exp(-c \cdot \Phi_{eq}))}_{\text{Acceptor removal}} + \underbrace{g_c \cdot \Phi_{eq}}_{\text{Acceptor introduction}}$$

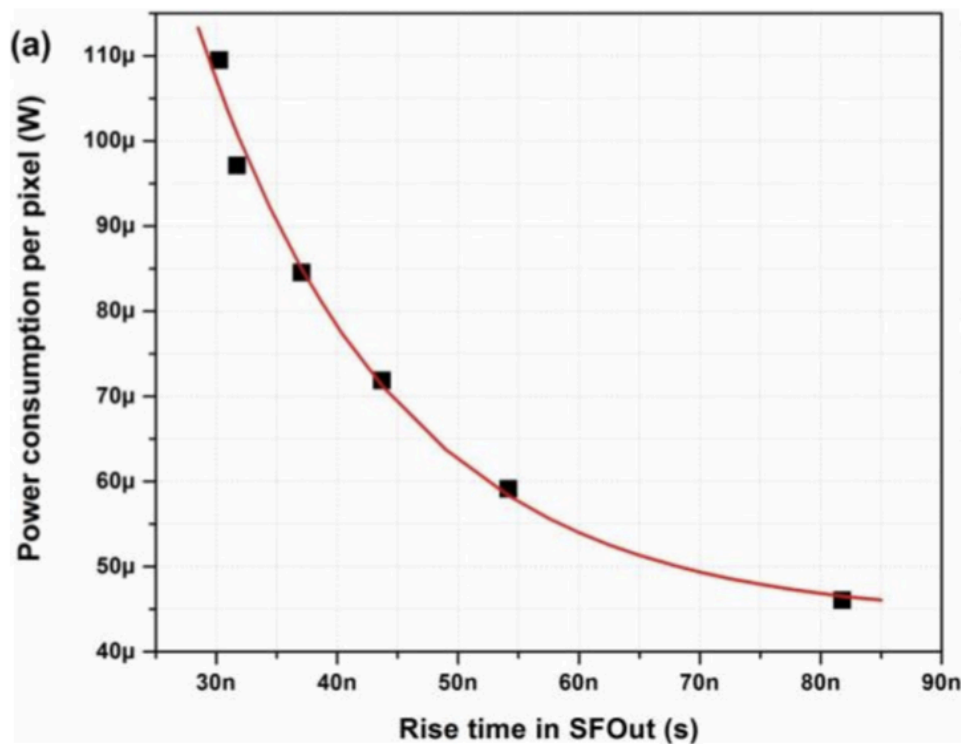
Initial doping

Acceptor removal

Acceptor introduction



Power vs. rise time

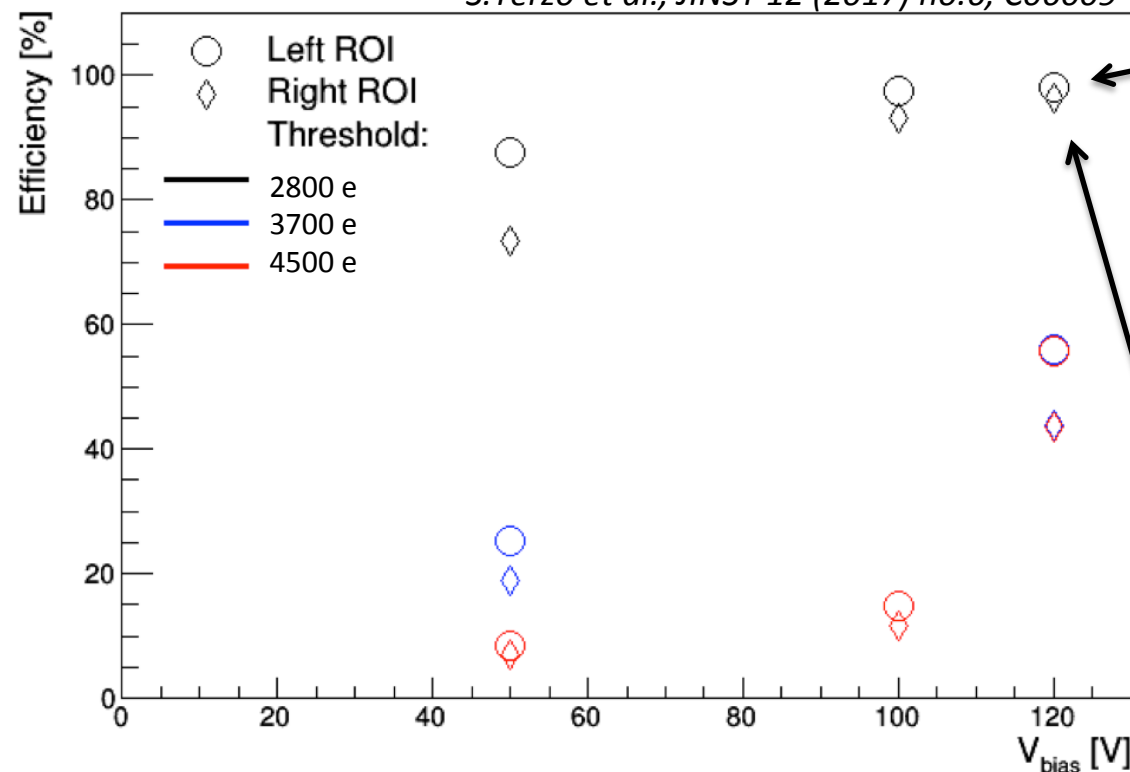


- Simulation of the power consumption as a function of the rise time for analog pixels with high gain
- For low gain pixels (-p-tub +extra capacitor) the rise time can go down to 20 ns with aggressive settings

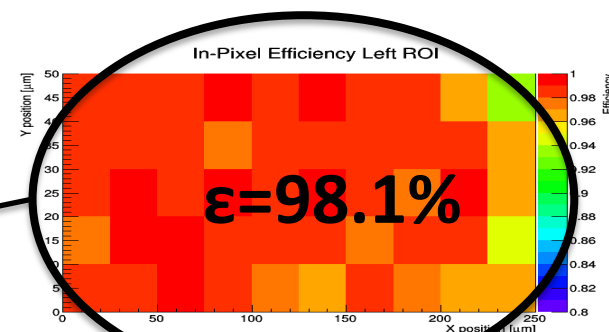
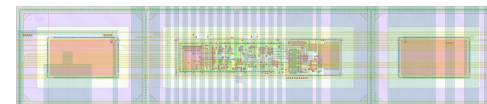
Test beam @ SpS in 2016

- Efficiency saturation depends on the threshold
 - Higher threshold requires more bias
→ increase the depletion depth
- Higher efficiency in the left matrix
 - Mean threshold right > mean threshold left
 - Right matrix: efficiency lost close to pixel edges

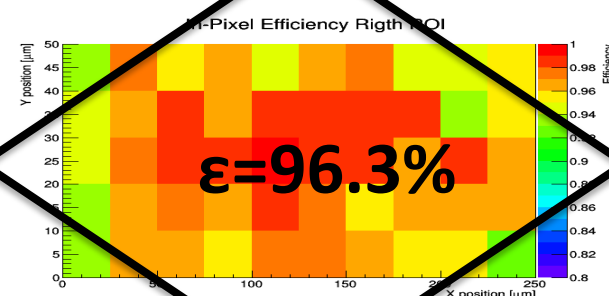
S.Terzo et al., JINST 12 (2017) no.6, C06009



In-pixel efficiency maps
at 120 V and Thr: 2800 e



Left matrix



Right matrix